

Notice of References Cited	Application/Control No. 10/766,776	Applicant(s)/Patent Under Reexamination DOAN, JONATHAN	
	Examiner Eric B. Chen	Art Unit 1765	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-5,057,187	10-1991	Shinagawa et al.	438/725
*	C	US-6,804,039	10-2004	Doan et al.	359/291
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	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

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	U	Wolf et al., Silicon Processing for the VLSI Era, 1986, Lattice Press, Vol. 1, pp. 179, 180, 200-201, 209-211, 216-219, 230-232, 374, 564, 570.
	V	Callister, Materials Science and Engineering, 1997, John Wiley & Sons, 4th ed., pp. 592, 593, 601.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.